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(54) METHOD OF MANUFACTURING PLASMA DISPLAY PANEL

(57)Abstract:

PROBLEM TO BE SOLVED: To provide a method of manufacturing a plasma display panel including a new forming process that enables to efficiently form a dielectric layer having a thicker film.

SOLUTION: This method comprises steps of forming film forming material layer by applying a paste phase composition containing glass powder, acrylic acid eater resin and solvent on a support film, transcribing the film forming material layer forming on the support film onto an outer surface of a glass substrate to which electrodes are fixed, and forming a dielectric layer in the outer surface of the glass substrate by sintering the transcribed film forming material layer.